



Union Internationale Pour La Science, La Technique et Les Applications du Vide
International Union for Vacuum Science, Technique and Applications
Internationale Union für Vakuum Forschung, Technik und Anwendung

Pierre Vinchon is the 2020 Medard W. Welch Scholarship winner

Martin Wuest, Martin.Wuest@inficon.com, IUVSTA Awards Committee Chair

The Medard W. Welch International Scholarship is awarded every year to support a young postgraduate scientist for working for up to one year in a country in which she/he has not previously studied.

The scholarship is graciously provided by **Mrs. Beth Howard** and **Mr. Kenneth Bro**, grandchildren of Medard W. Welch.

It is our pleasure to announce Dr. Pierre Vinchon as the 2020 Medard W. Welch Scholarship winner.



Dr. Pierre Vinchon

Pierre Vinchon began his studies at the Pierre and Marie Curie University in France where he obtained a B.Sc. in Fundamental Physics. He started his M.Sc at the same university and continued at the INRS (Institut national de la recherche scientifique) in Varennes (Quebec). His path then led to the University of Montreal where he studied graphene evolution under exposure of low-pressure inductively coupled Argon/B₂H₆ plasma.

Thanks to this award, his next station is scheduled to be at the lab of **Prof. Satoshi Hamaguchi** at the Center for Atomic and Molecular Technologies, Graduate School of Engineering, Osaka University, where he will work on surface reactions of Plasma Enhanced Atomic Layer Etching (PEALE) and Deposition (PEALD) experimentally and theoretically.

Pierre Vinchon statement: "I am honored to have been chosen for the Medard W. Welch Scholarship and I look forward to working with Prof. Hamaguchi at Osaka University. I am excited to further explore plasma-surface interactions in this stimulating environment."
